

c1 arranged to discharge said liquid chemical from said connecting pipe into said solvent in the piping system at a linear velocity that is significantly greater than a linear velocity of said solvent to produce said mixture solution at a described uniform concentration.

c2 8. (Twice Amended) The chemical supply system of claim 1, wherein said chemical discharging means comprises a capillary disposed in said connecting pipe.

Please enter the following new claim:

63. (New) A chemical supply system for supplying a mixture solution for cleaning a substrate, wherein said mixture solution includes a liquid chemical mixed and diluted with a solvent, said chemical supply system comprising:

at least one chemical reservoir that is easy to move, wherein said liquid chemical is stored in said chemical reservoir at a high concentration;

c3 a chemical supply means for sucking a predetermined quantity of said liquid chemical from said chemical reservoir and feeding said liquid chemical out;

a piping system connected to said chemical supply means and forming a flow passage in which said solvent flows, wherein said piping system includes a discharge portion for said mixture solution at an end portion thereof; and

a chemical discharging means arranged to discharge said liquid from said chemical supply means into said solvent in said piping system such that said mixture solution is produced at a desired concentration.

REMARKS/ARGUMENTS

Claims 1-61 are pending. Claims 16-61 remain withdrawn from consideration as being directed to a non-elected invention. Claims 1 and 8 are amended. Claim 63 is new.

Priority Claim

Applicant requests that the Examiner hold the submission of copies of the previously filed priority documents in abeyance. Copies of the priority documents will be forthcoming prior to any requirement for payment of a base issue fee.